

U.S. UTILITY Patent Application

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****CONTINUING DATA VERIFIED:**

**** FOREIGN APPLICATIONS VERIFIED:**

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Foreign priority claimed 35 USC 119 conditions met		<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO 011593
Verified and Acknowledged Examiners's initials			
TITLE : Axis determination apparatus, film-thickness measurement apparatus, deposition apparatus, axis determination method, and film-thickness measurement method			
U.S. DEPT. OF COM. PAT. & TM. PTO-436 (Rev. 12-91)			

U.S. DEPT. OF COMM. / PAT. & TM. PTO-436 (Rev. 12-61)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED		
			Total Claims	Print Claim for O.G.	
ISSUE FEE			DRAWING		
Amount Due	Date Paid	Primary Examiner	Sheets Drwg.	Figs.Drwg.	Print Fig.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner		
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